Erwin Peiner

List of Publications by Year
in descending order

		172443	254170
164	2,731	29	43
papers	citations	h-index	g-index

164	164	164	2117
all docs	docs citations	times ranked	citing authors

#	Article	IF	Citations
1	Dimensional-Nanopatterned Piezoresistive Silicon Microcantilever for Environmental Sensing. , 2022, , 19-47.		2
2	Using a Tip Characterizer to Investigate Microprobe Silicon Tip Geometry Variation in Roughness Measurements. Sensors, 2022, 22, 1298.	3.8	2
3	Retarded boron and phosphorus diffusion in silicon nanopillars due to stress induced vacancy injection. Journal of Applied Physics, 2022, 131, 075702.	2.5	1
4	Micromachined Silicon Cantilever Resonator-Based Humidity Sensors for Multifunctional Applications. , 2021, , .		2
5	Investigating the Trackability of Silicon Microprobes in High-Speed Surface Measurements. Sensors, 2021, 21, 1557.	3.8	4
6	Influence of eccentric nanoindentation on top surface of silicon micropillar arrays. Journal of Physics: Conference Series, 2021, 1837, 012008.	0.4	1
7	Enhancement of unsteady frequency responses of electro-thermal resonance MEMS cantilever sensors. Journal of Physics: Conference Series, 2021, 1837, 012003.	0.4	0
8	Ultrafine Aerosol Particle Sizer Based on Piezoresistive Microcantilever Resonators with Integrated Air-Flow Channel. Sensors, 2021, 21, 3731.	3.8	8
9	Performance of an Electrothermal MEMS Cantilever Resonator with Fano-Resonance Annoyance under Cigarette Smoke Exposure. Sensors, 2021, 21, 4088.	3.8	7
10	Customized piezoresistive microprobes for combined imaging of topography and mechanical properties. Measurement: Sensors, 2021, 15, 100042.	1.7	2
11	MEMS-Based Cantilever Sensor for Simultaneous Measurement of Mass and Magnetic Moment of Magnetic Particles. Chemosensors, 2021, 9, 207.	3.6	3
12	In-Line Measurement of the Surface Texture of Rolls Using Long Slender Piezoresistive Microprobes. Sensors, 2021, 21, 5955.	3.8	11
13	Versatilely tuned vertical silicon nanowire arrays by cryogenic reactive ion etching as a lithium-ion battery anode. Scientific Reports, 2021, 11, 19779.	3.3	36
14	Vertically Aligned n-Type Silicon Nanowire Array as a Free-Standing Anode for Lithium-Ion Batteries. Nanomaterials, 2021, 11, 3137.	4.1	21
15	Fabrication of a microcantilever-based aerosol detector with integrated electrostatic on-chip ultrafine particle separation and collection. Journal of Micromechanics and Microengineering, 2020, 30, 014001.	2.6	9
16	Piezoresistive Microcantilever with SAM-Modified ZnO-Nanorods@Silicon-Nanopillars for Room-Temperature Parts-per-Billion NO₂ Detection. ACS Applied Nano Materials, 2020, 3, 6609-6620.	5.0	19
17	Sampling and Mass Detection of a Countable Number of Microparticles Using on-Cantilever Imprinting. Sensors, 2020, 20, 2508.	3.8	4
18	Defect distribution in boron doped silicon nanostructures characterized by means of scanning spreading resistance microscopy. Journal of Applied Physics, 2020, 127, .	2.5	5

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19	In-Plane and Out-of-Plane MEMS Piezoresistive Cantilever Sensors for Nanoparticle Mass Detection. Sensors, 2020, 20, 618.	3.8	19
20	Calibrating a high-speed contact-resonance profilometer. Journal of Sensors and Sensor Systems, 2020, 9, 179-187.	0.9	1
21	UV-LED Photo-Activated Room Temperature NO2 Sensors Based on Nanostructured ZnO/AlN Thin Films. Proceedings (mdpi), 2019, 2, .	0.2	3
22	Indentation modulus and hardness investigation of crystalline silicon surfaces treated by inductively coupled plasma reactive ion etching. Journal of Physics: Conference Series, 2019, 1319, 012008.	0.4	1
23	Piezoresistive Microcantilevers 3D-Patterned Using Zno-Nanorods@Silicon-Nanopillars for Room-Temperature Ethanol Detection. , 2019, , .		3
24	Cantilever-Droplet-Based Sensing of Magnetic Particle Concentrations in Liquids. Sensors, 2019, 19, 4758.	3.8	11
25	ZNO Nanostructures Functionalized Piezoresistive Silicon Microcantilever Platform for Portable Gas Sensing. , 2019, , .		2
26	Improvement of frequency responses of an in-plane electro-thermal cantilever sensor for real-time measurement. Journal of Micromechanics and Microengineering, 2019, 29, 124006.	2.6	9
27	Nanomechanical Characterization of Vertical Nanopillars Using an MEMS-SPM Nano-Bending Testing Platform. Sensors, 2019, 19, 4529.	3.8	4
28	Ultra Low Power Mass-Producible Gas Sensor Based on Efficient Self-Heated GaN Nanorods. , 2019, , .		2
29	Efficient Self-Heating in Gallium Nitride Nanopillars for Ultra-Low-Power Mass-Producible Gas Sensors. , 2019, , .		0
30	Real-Time Frequency Tracking of an Electro-Thermal Piezoresistive Cantilever Resonator with ZnO Nanorods for Chemical Sensing. Chemosensors, 2019, 7, 2.	3.6	19
31	Thermoelectric Generators Fabricated from Large-Scale-Produced Zr-/Hf-Based Half-Heusler Compounds Using Ag Sinter Bonding. Journal of Electronic Materials, 2019, 48, 5363-5374.	2.2	3
32	Vertical GaN Nanowires and Nanoscale Light-Emitting-Diode Arrays for Lighting and Sensing Applications. ACS Applied Nano Materials, 2019, 2, 4133-4142.	5.0	44
33	Quantitative scanning spreading resistance microscopy on n-type dopant diffusion profiles in germanium and the origin of dopant deactivation. Journal of Applied Physics, 2019, 125, .	2.5	11
34	Cantilever Sensors. Sensors, 2019, 19, 2043.	3.8	5
35	Long Slender Piezo-Resistive Silicon Microprobes for Fast Measurements of Roughness and Mechanical Properties inside Micro-Holes with Diameters below 100 Âµm. Sensors, 2019, 19, 1410.	3.8	12
36	Piezoresistive microcantilevers for humidity sensing. Journal of Micromechanics and Microengineering, 2019, 29, 053003.	2.6	60

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37	Piezoelectric MEMS Resonators for Cigarette Particle Detection. Micromachines, 2019, 10, 145.	2.9	25
38	Strategy toward Miniaturized, Self-out-Readable Resonant Cantilever and Integrated Electrostatic Microchannel Separator for Highly Sensitive Airborne Nanoparticle Detection. Sensors, 2019, 19, 901.	3.8	11
39	Silicon Nanopillars with ZNO Nanorods by Nanosphere Lithography on a Piezoresistive Microcantilever. , 2019, , .		2
40	Fabrication of SiO₂ microcantilever arrays for mechanical loss measurements. Materials Research Express, 2019, 6, 045206.	1.6	1
41	Phase optimization of thermally actuated piezoresistive resonant MEMS cantilever sensors. Journal of Sensors and Sensor Systems, 2019, 8, 37-48.	0.9	8
42	Design of Miniaturized, Self-Out-Readable Cantilever Resonator for Highly Sensitive Airborne Nanoparticle Detection. Proceedings (mdpi), 2018, 2, .	0.2	0
43	Silicon Microcantilevers with ZnO Nanorods/Chitosan-SAMs Hybrids on Its Back Surface for Humidity Sensing. Proceedings (mdpi), 2018, 2, .	0.2	7
44	Optimizing a Cantilever Measurement System towards High Speed, Nonreactive Contact-Resonance-Profilometry. Proceedings (mdpi), 2018, 2, 889.	0.2	2
45	Area-Selective Growth of Aligned ZnO Nanorod Arrays for MEMS Device Applications. Proceedings (mdpi), 2018, 2, .	0.2	11
46	Nanoindentation of crystalline silicon pillars fabricated by soft UV nanoimprint lithography and cryogenic deep reactive ion etching. Sensors and Actuators A: Physical, 2018, 283, 65-78.	4.1	27
47	Large area contact resonance spectroscopy mapping system for on-the-machine measurements. , 2018, , .		1
48	Nanofabrication of SOI-Based Photonic Waveguide Resonators for Gravimetric Molecule Detection. Proceedings (mdpi), 2018, 2, 1055.	0.2	0
49	Fabrication and characterization of single-pair thermoelectric generators of bismuth telluride using silver-sintering technology. Materials Today: Proceedings, 2018, 5, 10401-10407.	1.8	2
50	Traceable Nanomechanical Metrology of GaN Micropillar Array. Advanced Engineering Materials, 2018, 20, 1800353.	3.5	11
51	Self-actuating and self-sensing ZNO nanorods/chitosan coated piezoresistive silicon microcantilever for humidit Y sensing. , 2018, , .		7
52	Fabrication of ZnO nanorods and Chitosan@ZnO nanorods on MEMS piezoresistive self-actuating silicon microcantilever for humidity sensing. Sensors and Actuators B: Chemical, 2018, 273, 276-287.	7.8	62
53	Contact resonance spectroscopy for on-the-machine manufactory monitoring. Sensors and Actuators A: Physical, 2018, 279, 501-508.	4.1	11
54	GaN nanowire arrays with nonpolar sidewalls for vertically integrated field-effect transistors. Nanotechnology, 2017, 28, 095206.	2.6	58

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55	High-speed microprobe for roughness measurements in high-aspect-ratio microstructures. Measurement Science and Technology, 2017, 28, 034009.	2.6	11
56	Analysis of asymmetric resonance response of thermally excited silicon micro-cantilevers for mass-sensitive nanoparticle detection. Journal of Micromechanics and Microengineering, 2017, 27, 064001.	2.6	33
57	Towards fabrication of 3D isotopically modulated vertical silicon nanowires in selective areas by nanosphere lithography. Microelectronic Engineering, 2017, 179, 74-82.	2.4	32
58	Large-area fabrication of silicon nanostructures by templated nanoparticle arrays. , 2017, , .		0
59	Size-selective electrostatic sampling and removal of nanoparticles on silicon cantilever sensors for air-quality monitoring. , 2017, , .		10
60	Nanomechanical Traceable Metrology of Vertically Aligned Silicon and Germanium Nanowires by Nanoindentation. Proceedings (mdpi), 2017, 1, 375.	0.2	3
61	Fabrication of ZnO Nanorods on MEMS Piezoresistive Silicon Microcantilevers for Environmental Monitoring. Proceedings (mdpi), 2017, 1, .	0.2	15
62	Gravimetric humidity sensor based on ZnO nanorods covered piezoresistive Si microcantilever. , 2017, , .		6
63	Asymmetric resonance response analysis of a thermally excited silicon microcantilever for mass-sensitive nanoparticle detection. Proceedings of SPIE, 2017, , .	0.8	1
64	Transferable micromachined piezoresistive force sensor with integrated double-meander-spring system. Journal of Sensors and Sensor Systems, 2017, 6, 121-133.	0.9	16
65	Asymmetric resonance frequency analysis of in-plane electrothermal silicon cantilevers for nanoparticle sensors. Journal of Physics: Conference Series, 2016, 757, 012006.	0.4	3
66	Double-meander spring silicon piezoresistive sensors as microforce calibration standards. Optical Engineering, 2016, 55, 091409.	1.0	8
67	Direct-reading Resonant Silicon Cantilever for Probing of Surface Deposits. Procedia Engineering, 2016, 168, 658-661.	1.2	1
68	Piezoresistive Silicon Cantilever Covered by ZnO Nanorods for Humidity Sensing. Procedia Engineering, 2016, 168, 1114-1117.	1.2	18
69	Enhanced performance of pocket-sized nanoparticle exposure monitor for healthy indoor environment. Building and Environment, 2016, 95, 13-20.	6.9	25
70	Microtactile Cantilever Resonators for Characterizing Surface Deposits. Procedia Engineering, 2015, 120, 861-864.	1.2	3
71	Development of silicon microforce sensors integrated with double meander springs for standard hardness test instruments. , 2015, , .		2
72	Investigation of Thermoelectric Parameters of Bi2Te3: TEGs Assembled using Pressure-Assisted Silver Powder Sintering-Based Joining Technology. Journal of Electronic Materials, 2015, 44, 2055-2060.	2.2	7

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73	Electrothermal piezoresistive cantilever resonators for personal measurements of nanoparticles in workplace exposure. Proceedings of SPIE, 2015, , .	0.8	3
74	Handheld personal airborne nanoparticle detector based on microelectromechanical silicon resonant cantilever. Microelectronic Engineering, 2015, 145, 96-103.	2.4	59
75	Smart sensors and calibration standards for high precision metrology. Proceedings of SPIE, 2015, , .	0.8	7
76	Fabrication of wear-resistant silicon microprobe tips for high-speed surface roughness scanning devices. Proceedings of SPIE, 2015, , .	0.8	2
77	Partially integrated cantilever-based airborne nanoparticle detector for continuous carbon aerosol mass concentration monitoring. Journal of Sensors and Sensor Systems, 2015, 4, 111-123.	0.9	22
78	Vertical silicon nanowire arrayâ€patterned microcantilever resonators for enhanced detection of cigarette smoke aerosols. Micro and Nano Letters, 2014, 9, 676-679.	1.3	26
79	Production of vertical nanowire resonators by cryogenic-ICPâ€“DRIE. Microsystem Technologies, 2014, 20, 759-767.	2.0	31
80	Finite element modeling and experimental proof of NEMS-based silicon pillar resonators for nanoparticle mass sensing applications. Microsystem Technologies, 2014, 20, 571-584.	2.0	31
81	A phase-locked loop frequency tracking system for portable microelectromechanical piezoresistive cantilever mass sensors. Microsystem Technologies, 2014, 20, 559-569.	2.0	44
82	In-plane-excited silicon nanowire arrays-patterned cantilever sensors for enhanced airborne particulate matter exposure detection. , 2014, , .		0
83	Thermoelectric Coolers with Sintered Silver Interconnects. Journal of Electronic Materials, 2014, 43, 2397-2404.	2.2	15
84	High-Temperature Performance of Stacked Silicon Nanowires for Thermoelectric Power Generation. Journal of Electronic Materials, 2013, 42, 2233-2238.	2.2	19
85	Nondestructive Evaluation of Diesel Spray Holes Using Piezoresistive Sensors. IEEE Sensors Journal, 2013, 13, 701-708.	4.7	22
86	Silicon Nanowire Resonators: Aerosol Nanoparticle Mass Sensing in the Workplace. IEEE Nanotechnology Magazine, 2013, 7, 18-23.	1.3	18
87	Silicon nanowire resonators for aerosol nanoparticle mass sensing. , 2013, , .		0
88	Silicon resonant nanopillar sensors for airborne titanium dioxide engineered nanoparticle mass detection. Sensors and Actuators B: Chemical, 2013, 189, 146-156.	7.8	63
89	Portable cantilever-based airborne nanoparticle detector. Sensors and Actuators B: Chemical, 2013, 187, 118-127.	7.8	50
90	Airborne engineered nanoparticle mass sensor based on a silicon resonant cantilever. Sensors and Actuators B: Chemical, 2013, 180, 77-89.	7.8	136

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91	Evaluation of photoresist-based nanoparticle removal method for recycling silicon cantilever mass sensors. Sensors and Actuators A: Physical, 2013, 202, 90-99.	4.1	30
92	Thermoelectric Properties of High-Doped Silicon from Room Temperature to 900ÂK. Journal of Electronic Materials, 2013, 42, 2381-2387.	2.2	69
93	Simulation and characterization of silicon nanopillar-based nanoparticle sensors. , 2013, , .		1
94	Femtogram aerosol nanoparticle mass sensing utilising vertical silicon nanowire resonators. Micro and Nano Letters, 2013, 8, 554-558.	1.3	38
95	MEMS-based silicon cantilevers with integrated electrothermal heaters for airborne ultrafine particle sensing. Proceedings of SPIE, 2013, , .	0.8	4
96	A closed-loop system for frequency tracking of piezoresistive cantilever sensors. , 2013, , .		0
97	Fabrication of vertical nanowire resonators for aerosol exposure assessment. Proceedings of SPIE, 2013, , .	0.8	0
98	Packaging of MEMS and MOEMS for harsh environments. Journal of Micro/ Nanolithography, MEMS, and MOEMS, 2012, 11, 021202-1.	0.9	6
99	Sinter-attach of high-temperature sensors for deep-drilling monitoring. , 2012, , .		1
100	Effect of Photoresist Coating on the Reusable Resonant Cantilever Sensors for Assessing Exposure to Airborne Nanoparticles. Procedia Engineering, 2012, 47, 302-305.	1.2	1
101	Femtogram Mass Measurement of Airborne Engineered Nanoparticles using Silicon Nanopillar Resonators. Procedia Engineering, 2012, 47, 289-292.	1.2	5
102	Sintering of Copper Particles for Die Attach. IEEE Transactions on Components, Packaging and Manufacturing Technology, 2012, 2, 1587-1591.	2.5	60
103	Nanowire silicon as a material for thermoelectric energy conversion. Microsystem Technologies, 2012, 18, 857-862.	2.0	19
104	Fabrication, packaging, and characterization of p-SOI Wheatstone bridges for harsh environments. Microsystem Technologies, 2012, 18, 869-878.	2.0	11
105	Determination of exposure to engineered carbon nanoparticles using a self-sensing piezoresistive silicon cantilever sensor. Microsystem Technologies, 2012, 18, 905-915.	2.0	9
106	Pick-and-Place Silver Sintering Die Attach of Small-Area Chips. IEEE Transactions on Components, Packaging and Manufacturing Technology, 2012, 2, 199-207.	2.5	42
107	Measurements of thermoelectric properties of silicon pillars. Sensors and Actuators A: Physical, 2011, 171, 48-48.	4.1	10
108	Thermal characterization of vertical silicon nanowires. Journal of Materials Research, 2011, 26, 1958-1962.	2.6	17

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109	Design and fabrication of piezoresistive p-SOI Wheatstone bridges for high-temperature applications. , 2011, , .		3
110	MEMS cantilever sensor for non-destructive metrology within high-aspect-ratio micro holes. Microsystem Technologies, 2010, 16, 1259-1268.	2.0	8
111	Shallow and deep dry etching of silicon using ICP cryogenic reactive ion etching process. Microsystem Technologies, 2010, 16, 863-870.	2.0	34
112	GaN and LED structures grown on preâ€patterned silicon pillar arrays. Physica Status Solidi C: Current Topics in Solid State Physics, 2010, 7, 84-87.	0.8	11
113	GaN nanorods and LED structures grown on patterned Si and AlN/Si substrates by selective area growth. Physica Status Solidi C: Current Topics in Solid State Physics, 2010, 7, 2224-2226.	0.8	14
114	Characterization of diesel injectors using piezoresistive sensors. , 2010, , .		5
115	Surface finish improvement of deep micro bores monitored using an active MEMS cantilever probe. , 2010, , .		5
116	Die-attach for high-temperature applications using fineplacer-pressure-sintering (FPS). , 2010, , .		8
117	Neue taktile Sensoren fÃ¼r die Mikro- und NanotechnikNew Tactile Sensors for Micro- and Nanotechnology. TM Technisches Messen, 2009, 76, 323-331.	0.7	4
118	Capabilities of ICP-RIE cryogenic dry etching of silicon: review of exemplary microstructures. Journal of Micromechanics and Microengineering, 2009, 19, 105005.	2.6	44
119	Threeâ€dimensionally structured silicon as a substrate for the MOVPE growth of GaN nanoLEDs. Physica Status Solidi (A) Applications and Materials Science, 2009, 206, 1194-1198.	1.8	8
120	Form measurement inside fuel injector nozzle spray holes. Microelectronic Engineering, 2009, 86, 984-986.	2.4	45
121	Silicon cantilever sensor for micro-/nanoscale dimension and force metrology. Microsystem Technologies, 2008, 14, 441-451.	2.0	16
122	Mechanical spectroscopy of thin polystyrene films. Polymer, 2008, 49, 2115-2118.	3.8	6
123	Gallium nitride heterostructures on 3D structured silicon. Nanotechnology, 2008, 19, 405301.	2.6	10
124	Slender Tactile Sensor for Contour and Roughness Measurements Within Deep and Narrow Holes. IEEE Sensors Journal, 2008, 8, 1960-1967.	4.7	37
125	Kontur-, Rauheits- und Kraftmesstechnik mit Silizium-Cantileversonden (Shape, Roughness and Force) Tj ETQq1 1 0.784314 rgBT /Ove	0.7	6
126	Slender Tactile Sensor for High-Aspect-Ratio Micro Metrology. , 2007, , .		4

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127	Silicon cantilever sensor for micro-/nanoscale dimension and force metrology. , 2007, , .		1
128	Diamond-like carbon for MEMS. Journal of Micromechanics and Microengineering, 2007, 17, S83-S90.	2.6	44
129	Longitudinal and transversal piezoresistive effect in hydrogenated amorphous carbon films. Thin Solid Films, 2007, 515, 8028-8033.	1.8	30
130	The piezoresistive effect in diamond-like carbon films. Journal of Micromechanics and Microengineering, 2007, 17, S77-S82.	2.6	23
131	Transport and optical properties of amorphous carbon and hydrogenated amorphous carbon films. Applied Surface Science, 2006, 252, 5387-5390.	6.1	61
132	Micro force sensor with piezoresistive amorphous carbon strain gauge. Sensors and Actuators A: Physical, 2006, 130-131, 75-82.	4.1	60
133	Piezoresistive gauge factor of hydrogenated amorphous carbon films. Journal of Micromechanics and Microengineering, 2006, 16, S75-S81.	2.6	27
134	Force calibration of stylus instruments using silicon microcantilevers. Sensors and Actuators A: Physical, 2005, 123-124, 137-145.	4.1	18
135	Piezoresistive cantilever as portable micro force calibration standard. Journal of Micromechanics and Microengineering, 2003, 13, S171-S177.	2.6	84
136	Growth of InP Layers on Nanometer-Scale Patterned Si Substrates. Crystal Growth and Design, 2003, 3, 89-93.	3.0	20
137	The effect of threading dislocations on optical absorption and electron scattering in strongly mismatched heteroepitaxial IIIÂV compound semiconductors on silicon. Journal of Physics Condensed Matter, 2002, 14, 13195-13201.	1.8	13
138	Condition monitoring with axle box bearings using resonant microelectromechanical sensors. Journal of Micromechanics and Microengineering, 2002, 12, 479-485.	2.6	2
139	Micromachining of silicon carbide on silicon fabricated by low-pressure chemical vapour deposition. Journal of Micromechanics and Microengineering, 2002, 12, 380-384.	2.6	12
140	Hetero-micromachining of epitaxial III/V compound semiconductors. Sensors and Actuators A: Physical, 2000, 85, 324-329.	4.1	6
141	Temperature dependence of residual stress in epitaxial GaAs/Si(100) films determined from photoreflectance spectroscopy data. Semiconductors, 2000, 34, 73-80.	0.5	8
142	Fractures properties of InP microcantilevers by hetero-micromachining. Sensors and Actuators A: Physical, 1999, 76, 395-402.	4.1	10
143	Micromachined resonator for cavitation sensing. Sensors and Actuators A: Physical, 1999, 76, 266-272.	4.1	7
144	A micromachined vibration sensor based on the control of power transmitted between optical fibres. Sensors and Actuators A: Physical, 1998, 65, 23-29.	4.1	13

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145	Microelectromechanical vibration sensor with optical interconnects. Journal of Microelectromechanical Systems, 1998, 7, 56-61.	2.5	8
146	Characterization of surface damage in dry-etched InP. Semiconductor Science and Technology, 1997, 12, 755-759.	2.0	17
147	A low-frequency micromechanical resonant vibration sensor for wear monitoring. Sensors and Actuators A: Physical, 1997, 62, 616-620.	4.1	27
148	High-quality In0.53Ga0.47As on exactly (001)-oriented Si grown by metal-organic vapour-phase epitaxy. Journal of Crystal Growth, 1997, 172, 44-52.	1.5	13
149	Performance of InGaAs metal-semiconductor-metal photodetectors on Si. IEEE Photonics Technology Letters, 1996, 8, 670-672.	2.5	17
150	The effect of dislocations on the optical absorption of heteroepitaxial InP and GaAs on Si. Journal of Applied Physics, 1996, 79, 9273-9277.	2.5	17
151	The distribution of charge concentration in InP/Si. Journal of Applied Physics, 1995, 78, 224-228.	2.5	16
152	A procedure for temperatureâ€dependent, differential van der Pauw measurements. Review of Scientific Instruments, 1995, 66, 4271-4276.	1.3	4
153	Doping Profile Analysis in Si by Electrochemical Capacitanceâ€Voltage Measurements. Journal of the Electrochemical Society, 1995, 142, 576-580.	2.9	100
154	The effect of dislocations on the transport properties of III/Vâ€compound semiconductors on Si. Journal of Applied Physics, 1995, 78, 6141-6146.	2.5	13
155	Effect of III/V-Compound Epitaxy on Si Metal-Oxide-Semiconductor Circuits. Japanese Journal of Applied Physics, 1994, 33, 3628-3634.	1.5	17
156	Wet Chemical Etching of Alignment Vâ€Grooves in (100) InP through Titanium or In0.53Ga0.47As Masks. Journal of the Electrochemical Society, 1994, 141, 1594-1599.	2.9	28
157	Scattering mechanisms and defects in InP epitaxially grown on (001) Si substrates. Journal of Applied Physics, 1994, 76, 4705-4712.	2.5	15
158	Dopant activation energy and hole effective mass in heavily Zn-Doped InP. Journal of Electronic Materials, 1994, 23, 935-941.	2.2	12
159	A Theoretical Model of InP Mass Transport. Japanese Journal of Applied Physics, 1993, 32, 234-238.	1.5	4
160	Anisotropy and Lateral Homogeneity of InP-Mass Transport. Japanese Journal of Applied Physics, 1992, 31, L1153-L1156.	1.5	3
161	A new maskless selectiveâ€growth process for InP on (100) Si. Journal of Applied Physics, 1992, 72, 4366-4368.	2.5	17
162	Anodic Dissolution during Electrochemical Carrierâ€Concentration Profiling of Silicon. Journal of the Electrochemical Society, 1992, 139, 552-557.	2.9	30

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163	Automatic counting of etch Pits in InP. Journal of Electronic Materials, 1992, 21, 887-892.	2.2	12
164	Compliant Tactile Sensors for High-Aspect-Ratio Form Metrology. , 0, , .		3